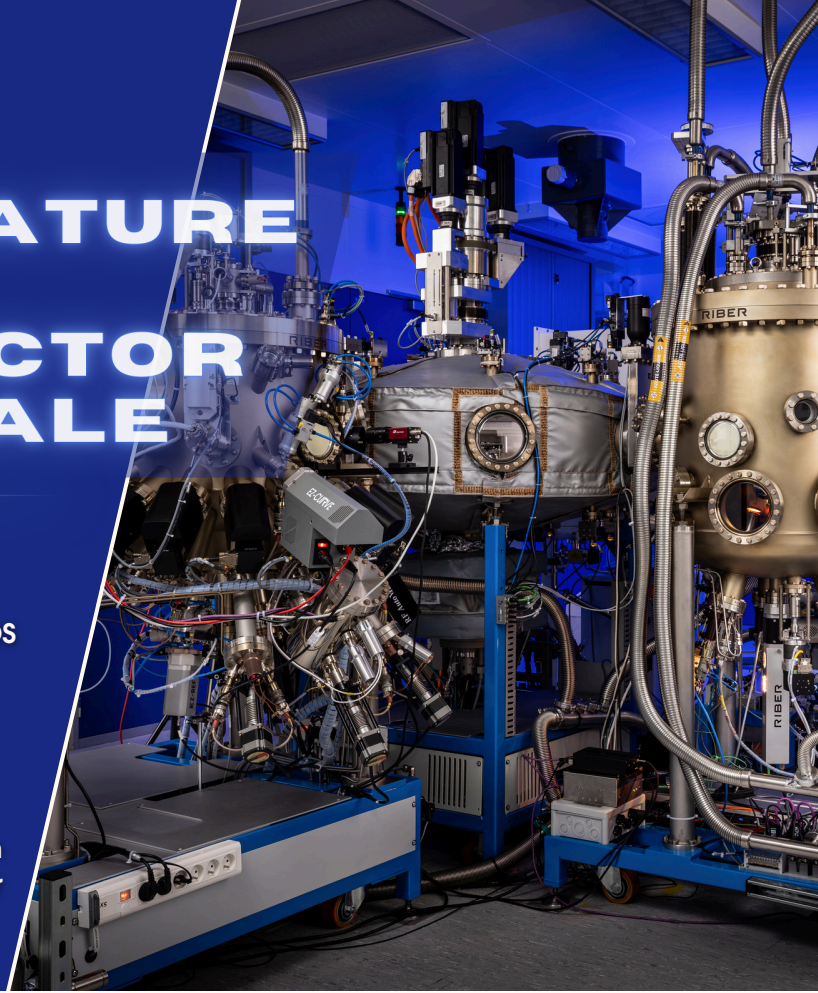


RIBER

LOW TEMPERATURE GROWTH OF SUPERCONDUCTOR AT WAFER SCALE

RIBER's SUPRA hybrid platform is a fully automated UHV system dedicated for the growth of semiconducting - superconductor heterostructures compatible with CMOS standards.

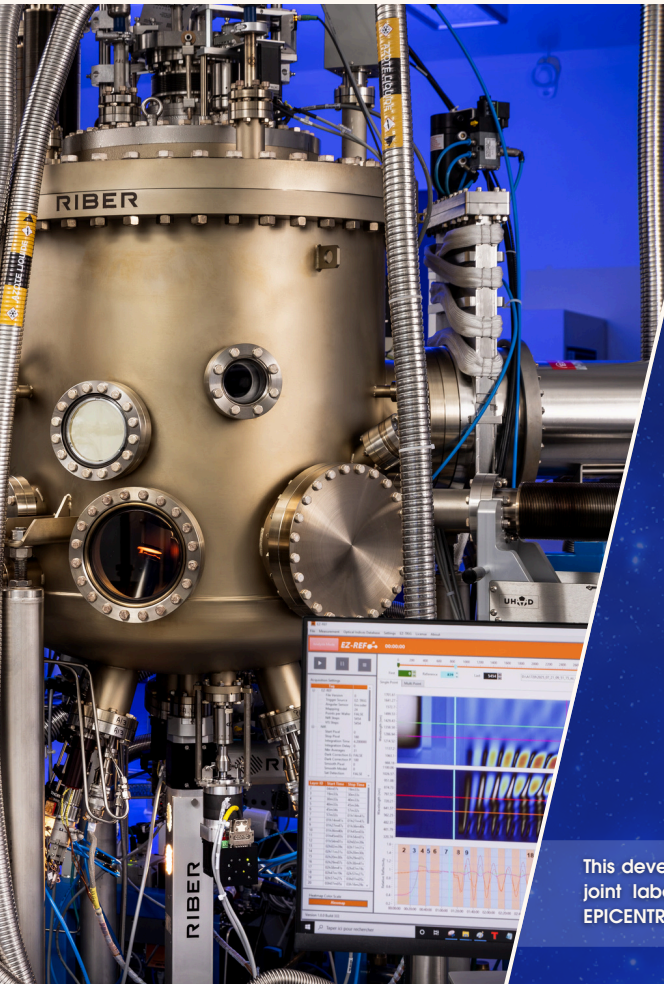
This new platform is first a III-V growth chamber that is directly connected to our new patented low temperature cryogenic metal chamber - the SUPRA chamber - for superconducting materials. An oxidation capability is available either within the SUPRA chamber or in a dedicated oxidation chamber.



GROWTH TEMPERATURE < 100K WITH WAFER ROTATING

OXIDATION CAPABILITY

INTEGRATES EZ INSTRUMENTS FOR HIGH GROWTH CONTROL



SUPRA CHAMBER

UHV environment

Deposition temperature <100K for 3 hours

Deposition with wafer rotating

Oxidation capability

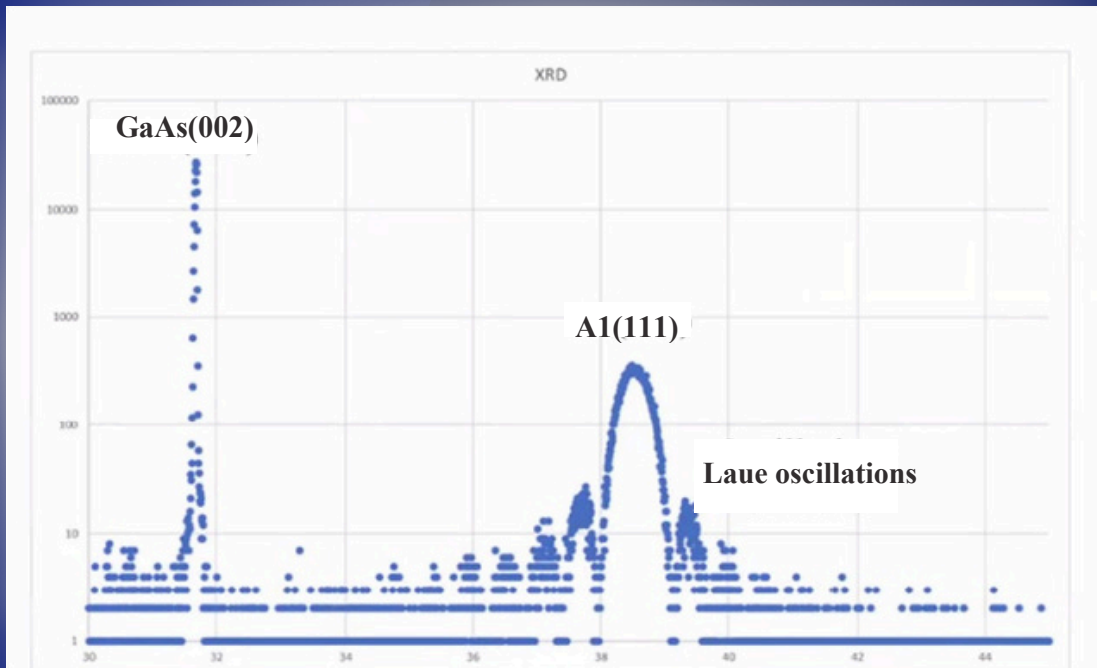
This development and the results presented were carried out as part of the EPICENTRE joint laboratory with LAAS-CNRS Toulouse (a member of Renatech network). The EPICENTRE platform used is the one shown in the photo.



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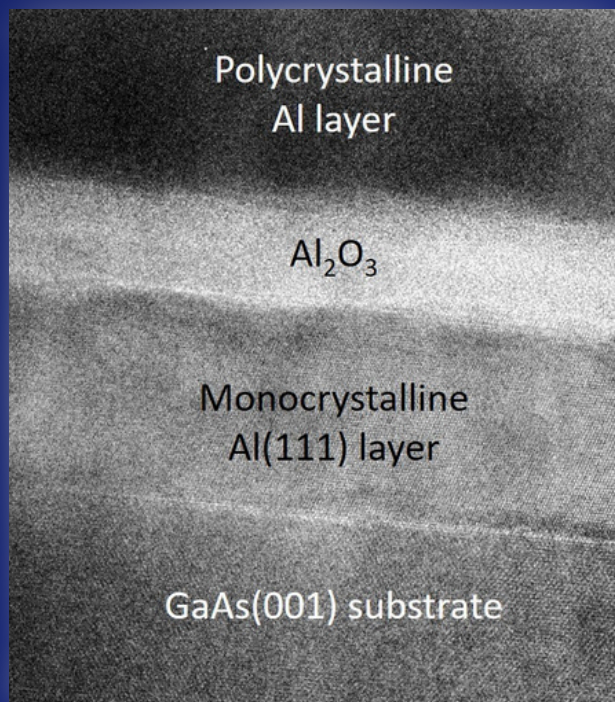
RIBER



Al deposition on GaAs substrate with 2D morphology and monocrystalline phase. XRD measurement of a 18nm thick Al grown at $T=92K$ on a GaAs (002) substrate

RIBER

First Josephson junction achieved in the framework of Epicentre by Sébastien Plissard and his team.



Scan the QR code to visit our EZ Instruments website for more informations